T-765 P.005/010 F-452 JAN **2** 7 2006

ASA-481-10

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

N. HASEGAWA et al.

Serial No. 10/777,060

Group Art Unit: 1756

Filed: February 13, 2004

Examiner: Stephen D. ROSASCO

For: PHOTOMASK AND PATTERN

FORMING METHOD EMPLOYING

THE SAME

## REPLY

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

January 27, 2006

Sir:

In Reply to the Office Action mailed August 11, 2005, the Applicants request reconsideration as follows. A Petition for a Three-Month Extension of Time accompanies this Reply.